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January 23, 2007 Flor S. Neafus Signature Date

Patent Attorney's Docket No. 42P10077D2 IN THE UNITED STATES PATENT AND TRADEMARK OFFICE e Patent Application of: Dougherty, Thomas M. Qing Ma et al. Examiner: Application No.: 10/763,779 Art Unit: 2834 Filed: January 22, 2004 MICRO-ELECTROMECHANICAL For: STRUCTURE RESONATOR FREQUENCY ADJUSTMENT USING RADIANT ENERGY TRIMMING AND LASER/FOCUSED ION BEAM ASSISTED DEPOSITION

> Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

Enclosed is a copy of Information Disclosure Citation Form PTO-1449 or PTO/SB/08 together with copies of the documents cited on that form. It is respectfully requested that the cited documents be considered and that the enclosed copy of Information Disclosure Citation Form PTO-1449 or PTO/SB/08 be initialed by the Examiner to indicate such consideration and a copy thereof returned to applicant(s).

Pursuant to 37 C.F.R. § 1.97, the submission of this Information Disclosure Statement is not to be construed as a representation that a search has been made and is not to be construed as an admission that the information cited in this statement is material to patentability.

Pursuant to 37 C.F.R. § 1.97, this Information Disclosure Statement is being submitted under one of the following (as indicated by an "X" to the left of the appropriate paragraph):

______ 37 C.F.R. §1.97(b).

37 C.F.R. §1.97(b).
37 C.F.R. §1.97(c). If so, then enclosed with this Information Disclosure Statement is one of the following:
A statement pursuant to 37 C.F.R. §1.97(e) or
A check for \$180.00 for the fee under 37 C.F.R. § 1.17(p).
37 C.F.R. §1.97(d). If so, then enclosed with this Information Disclosure Statement are the following:

- (1) A statement pursuant to 37 C.F.R. §1.97(e); and
- (2) A check for \$180.00 for the fee under 37 C.F.R. §1.17(p) for submission of the Information Disclosure Statement.

If there are any additional charges, please charge Deposit Account No. 02-2666.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP

Dated: <u>/-23-07</u>

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Substitute for Form 1449/PTO				Complete if Known					
STATEMENT BY APPLICANT (use as many sheets as necessary)					Application Number 10/763,779				
				Filing Date	January 22, 2004				
				First Named Inventor:	Qing Ma et al.				
				Art Unit	2834				
				Examiner Name	Thomas M. Dougherty				
Sheet	1	of 1		Attorney Docket Number	42P10077D2				
NON PATENT LITERATURE DOCUMENTS									
Examiner Initials*	Cite No ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published							
	1.	Application No. 09/738,118, Filing date 12/15/2000, Qing Ma et al., "A PROCESS OF MAKING A MICRO-ELECTROMECHANICAL STRUCTURE RESONATOR WITH FREQUENCY ADJUSTMENT," Office Action mailed 06/15/2004. (42P10077)							
	2.	Application No. 09/738,118, Filing date 12/15/2000, Qing Ma et al., "A PROCESS OF MAKING A MICRO-ELECTROMECHANICAL STRUCTURE RESONATOR WITH FREQUENCY ADJUSTMENT," Office Action mailed 12/17/2004. (42P10077)							
	3.	MAKING A MICE FREQUENCY AL	RO-ELECTROMEO DJUSTMENT," Of	date 12/15/2000, Qing Ma et a CHANICAL STRUCTURE RES	SONATOR WITH . (42P10077)				
	4.	MAKING A MICF	RO-ELECTROME	date 12/15/2000, Qing Ma et a CHANICAL STRUCTURE RES	SONATOR WITH				
	5.	MAKING A MICF	RO-ELECTROME	date 12/15/2000, Qing Ma et a CHANICAL STRUCTURE RES	SONATOR WITH				
	6.	ELECTROMECH USING RADIAN	HANICAL STRUCT T ENERGY TRIMI	date 03/10/2003, Qing Ma et a TURE RESONATOR FREQUE MING AND LASER/FOCUSED ed 09/15/2003. (42P10077D)	ENCY ADJUSTMENT				
	7.	Application No. 10/386,062, Filing date 03/10/2003, Qing Ma et al., "MICRO- ELECTROMECHANICAL STRUCTURE RESONATOR FREQUENCY ADJUSTMENT USING RADIANT ENERGY TRIMMING AND LASER/FOCUSED ION BEAM ASSISTED DEPOSITION," Office Action mailed 12/04/2003. (42P10077D)							
	8.			date 03/19/2004, Qing Ma et a e Action mailed 12/13/2005. (4					
	9.			date 03/19/2004, Qing Ma et a e Action mailed 10/05/2006. (4					

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Examiner		Date	
Signature	5 mm 5	Considered	

^{*}Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Applicant's unique citation designation number (optional). ²Applicant is to place a check mark here if English Translation is attached.
This collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SENT FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450. If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.